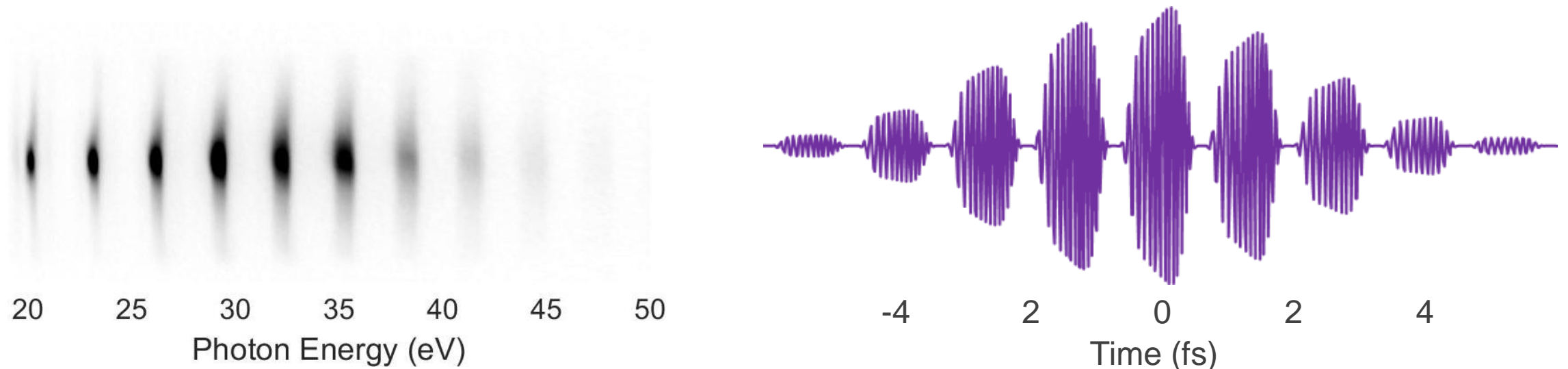


# High-harmonic generation and EUV Science

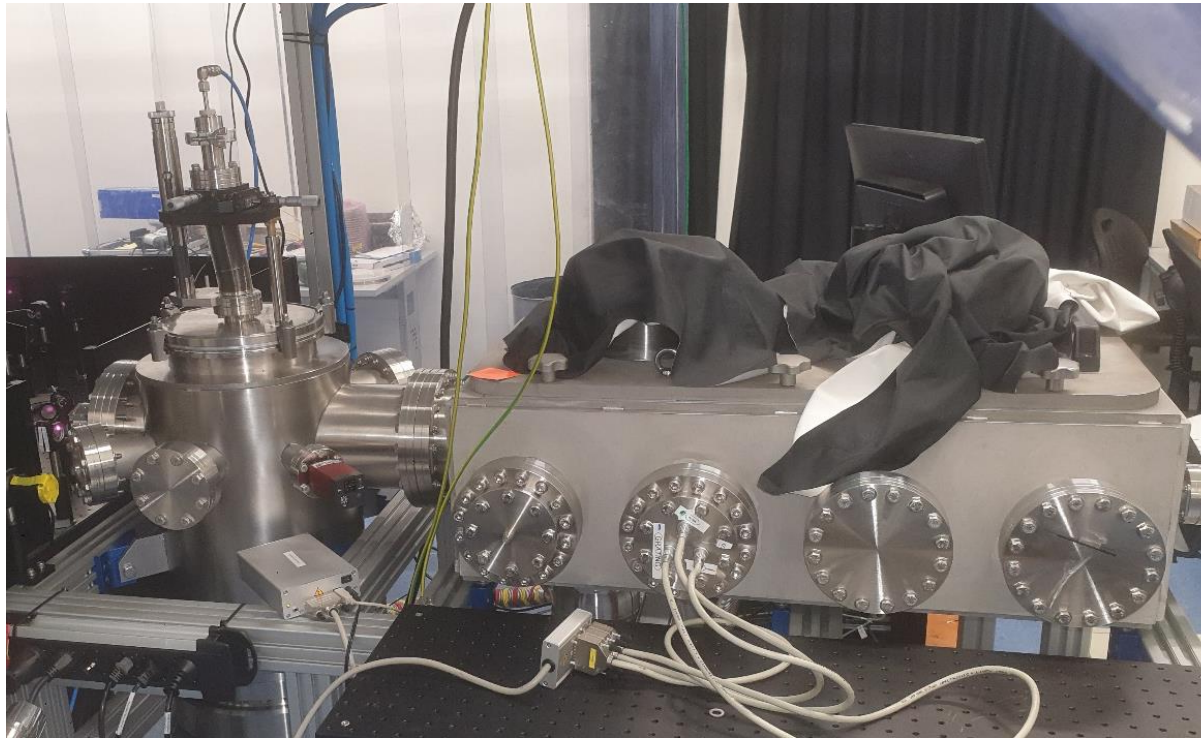
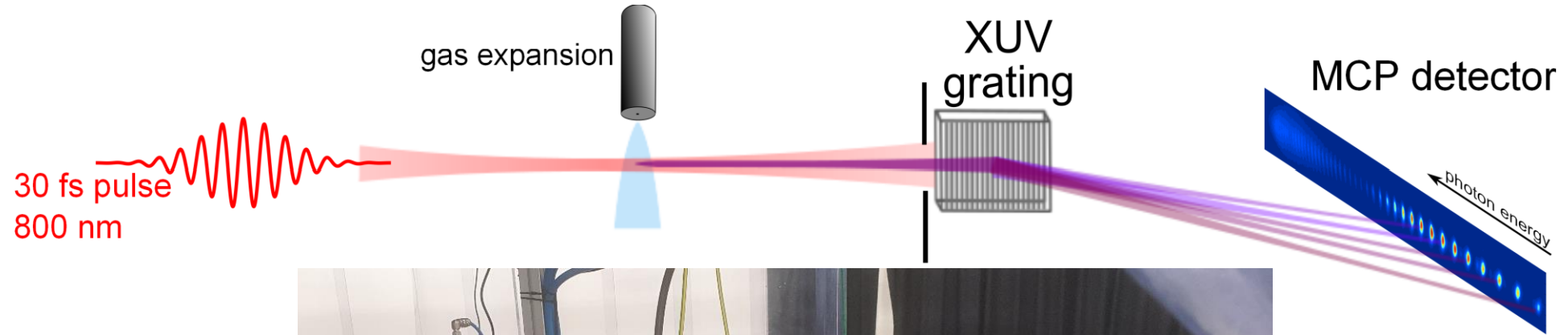
**Peter M. Kraus**

*Advanced Research Center for Nanolithography (ARCNL), Amsterdam, The Netherlands.*  
EUV source workshop, 04.11.2019, Amsterdam, The Netherlands.

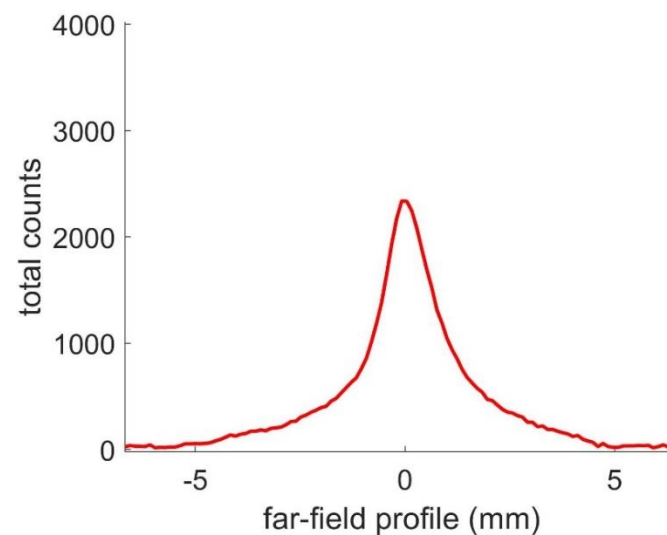
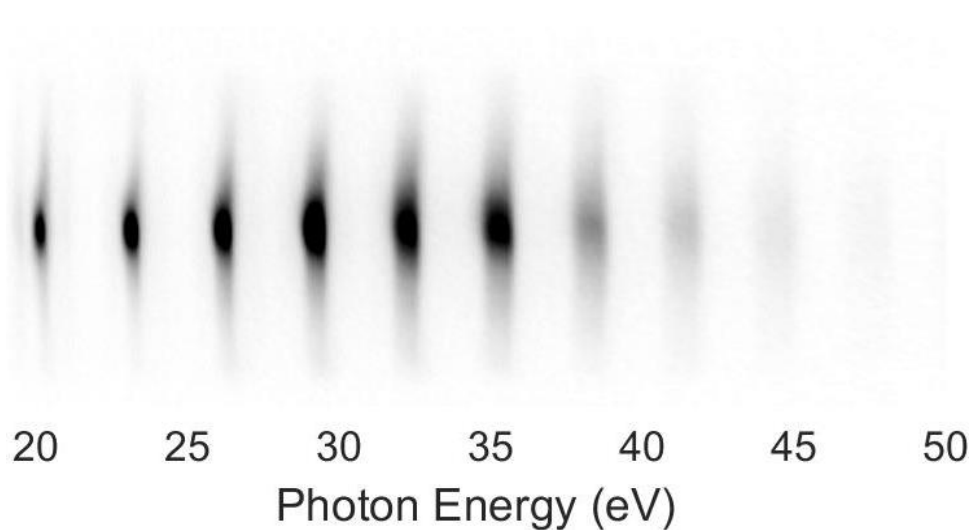
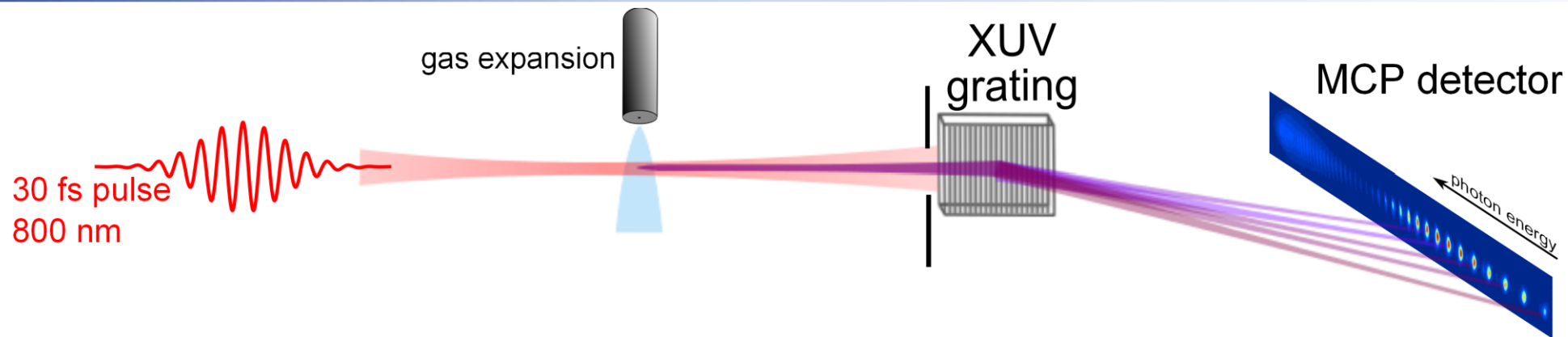




# An outside look at HHG

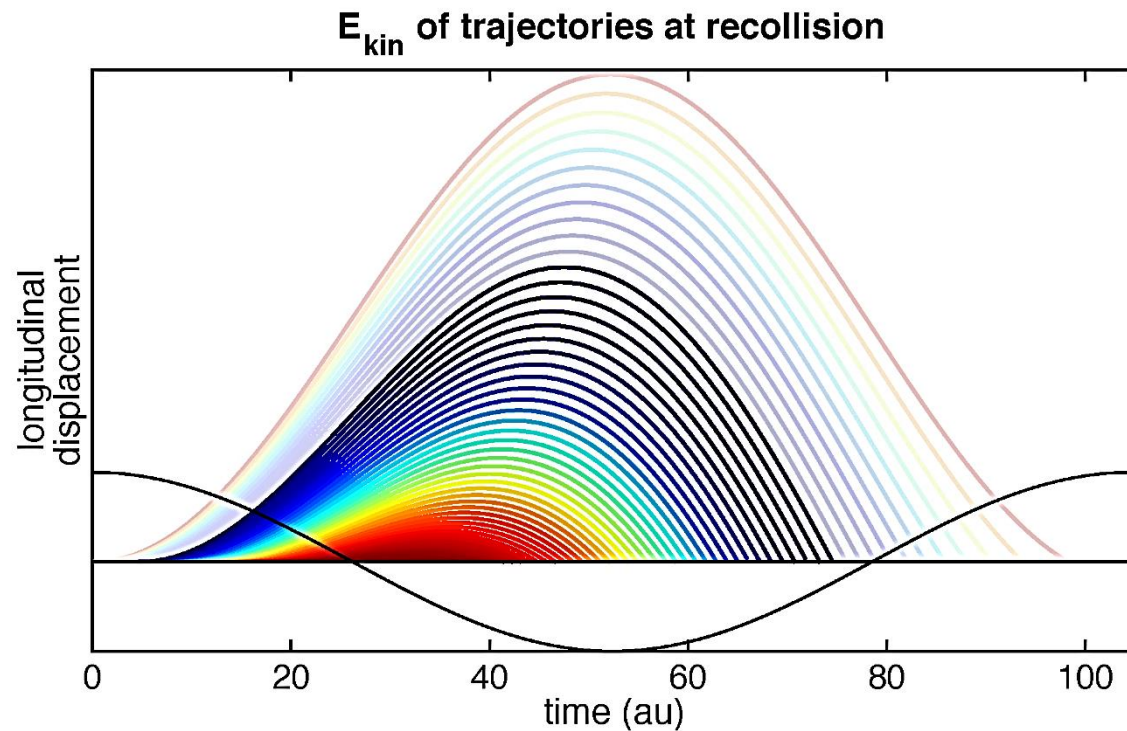
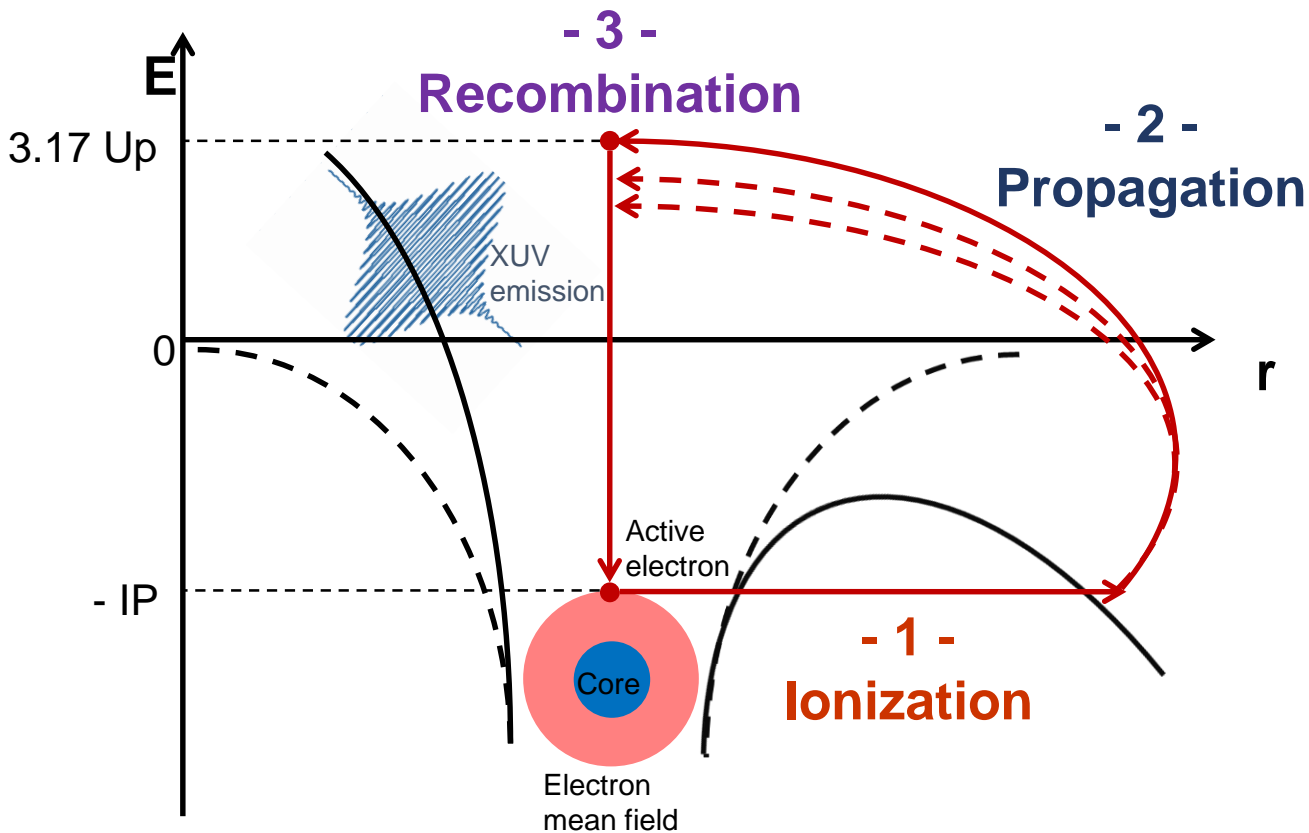


# An outside look at HHG



**Double Gaussian beam profile; pulse energy is lost in wings.  
Broad wings prohibit imaging of embedded structures.**

# An inside look into HHG

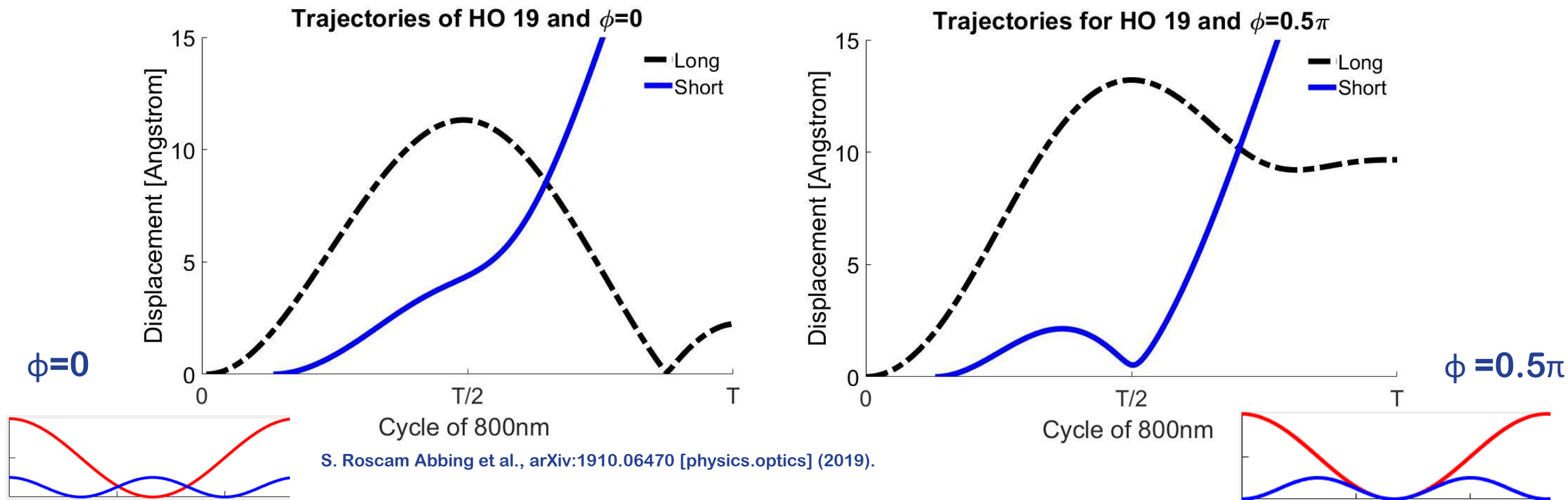


C. Hofmann et al., *Applied Sciences*, 8, 341 (2018)

For each generated energy there are two electron trajectories contributing:  
*Long and short trajectories*

# Trajectory selection in two-color HHG

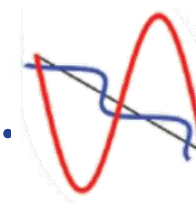
Adding an orthogonally polarized 400nm pulse changes the trajectories of the electrons.



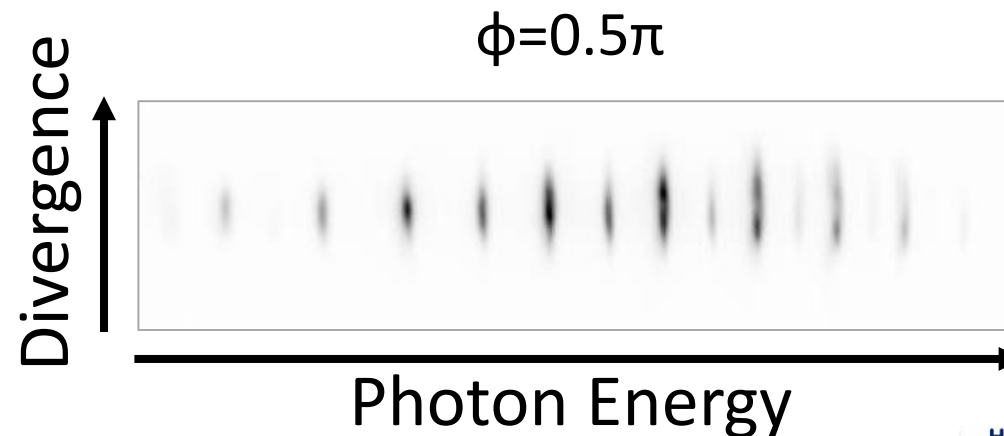
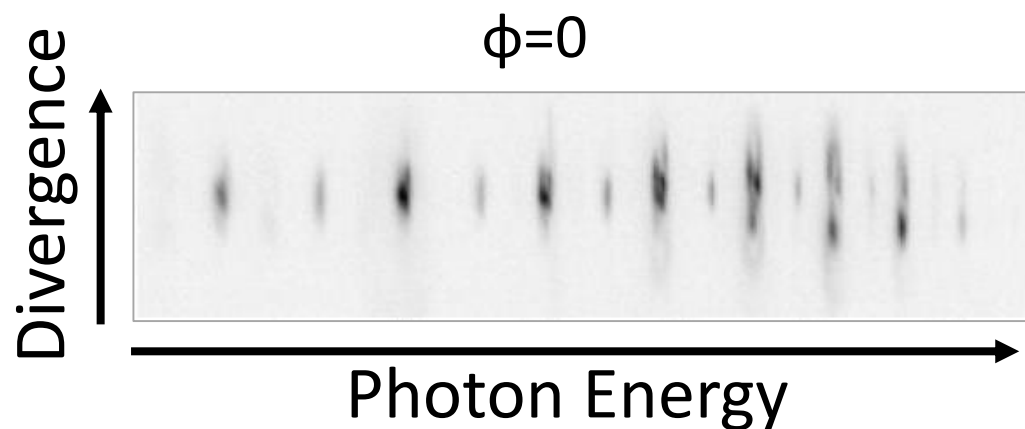
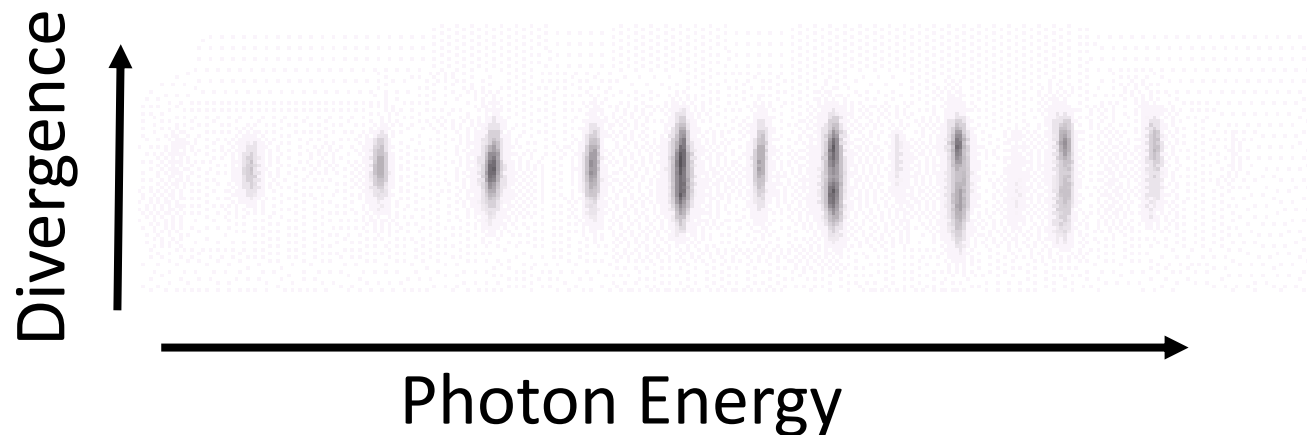
$\phi$ : relative phase between 800 nm and 400 nm fields

# Two-color HHG controls divergence

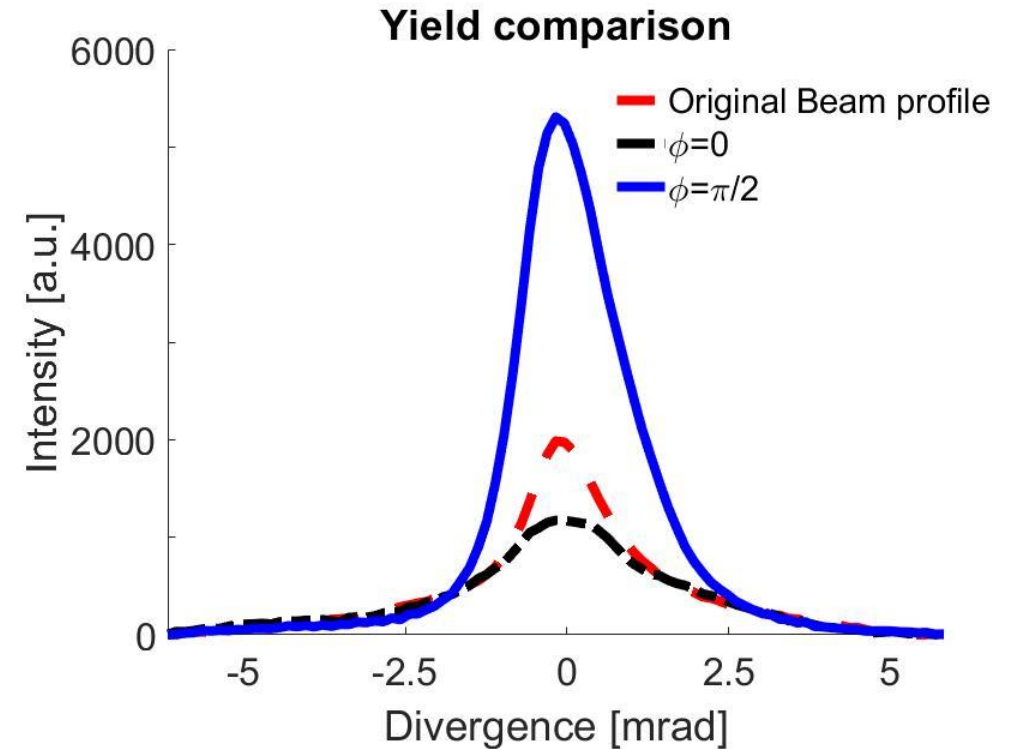
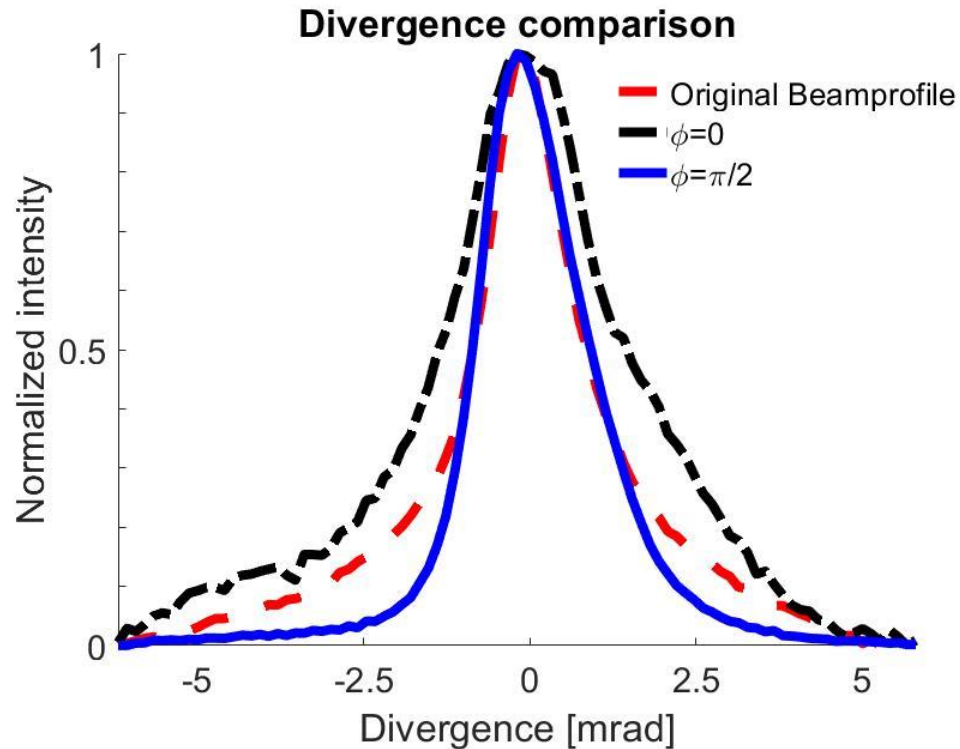
Video: HHG signal as function of phase of two-color field.



800 nm  
400 nm (orthog. pol.)  
15% rel. int.



# Divergence in HHG



Adding a perpendicular 400 nm pulse to the generation process enables divergence control.

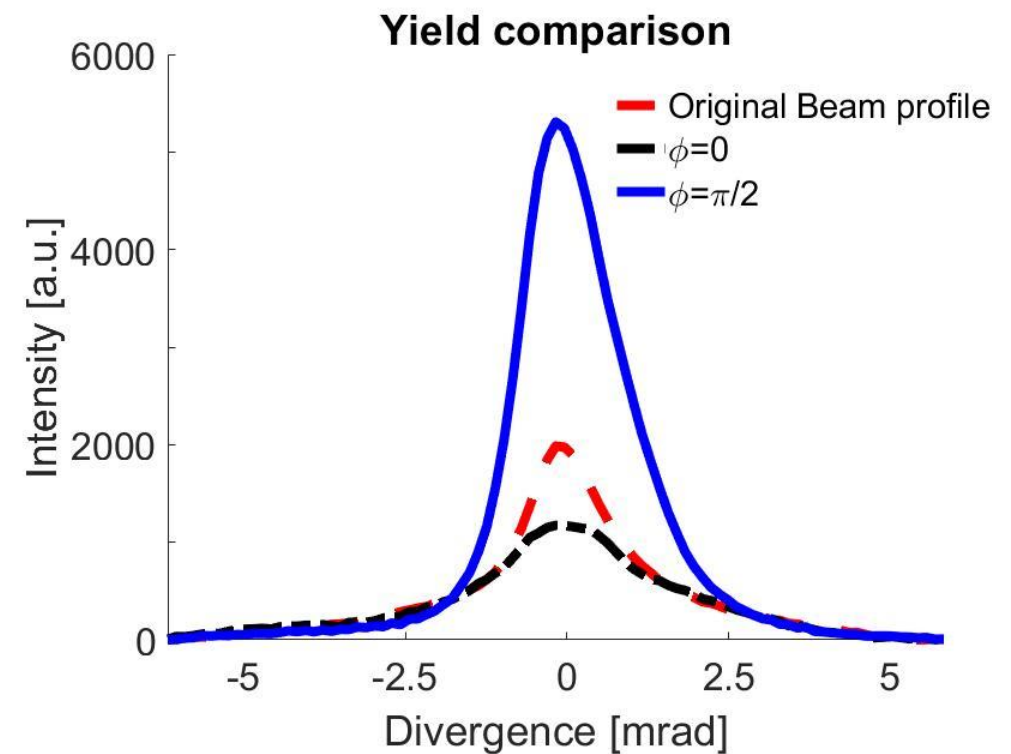
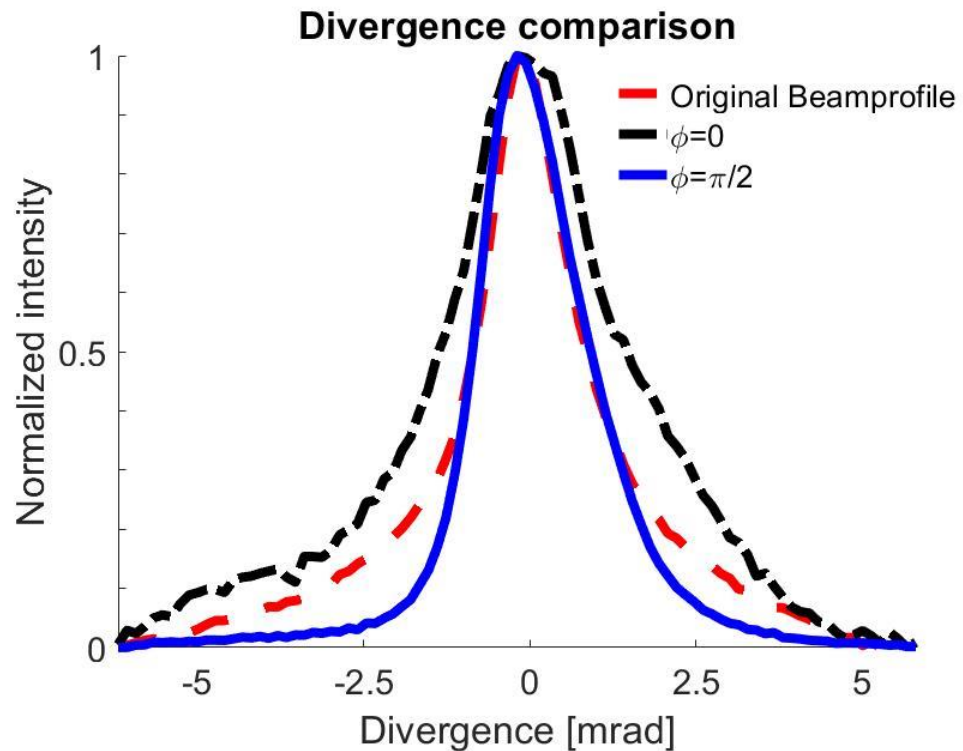
When selecting short trajectories, the total photon flux increases as well!

The optics are easy to implement.

The scheme enables micro-focussing of HHG



# Divergence in HHG



**Poster: “Divergence Control of High-harmonic Generation Enables High-brightness extreme-ultraviolet sources”**  
by Sylvianne Roscam Abbing

**Preprint: S. Roscam Abbing et al., arXiv:1910.06470 [physics.optics] (2019).**

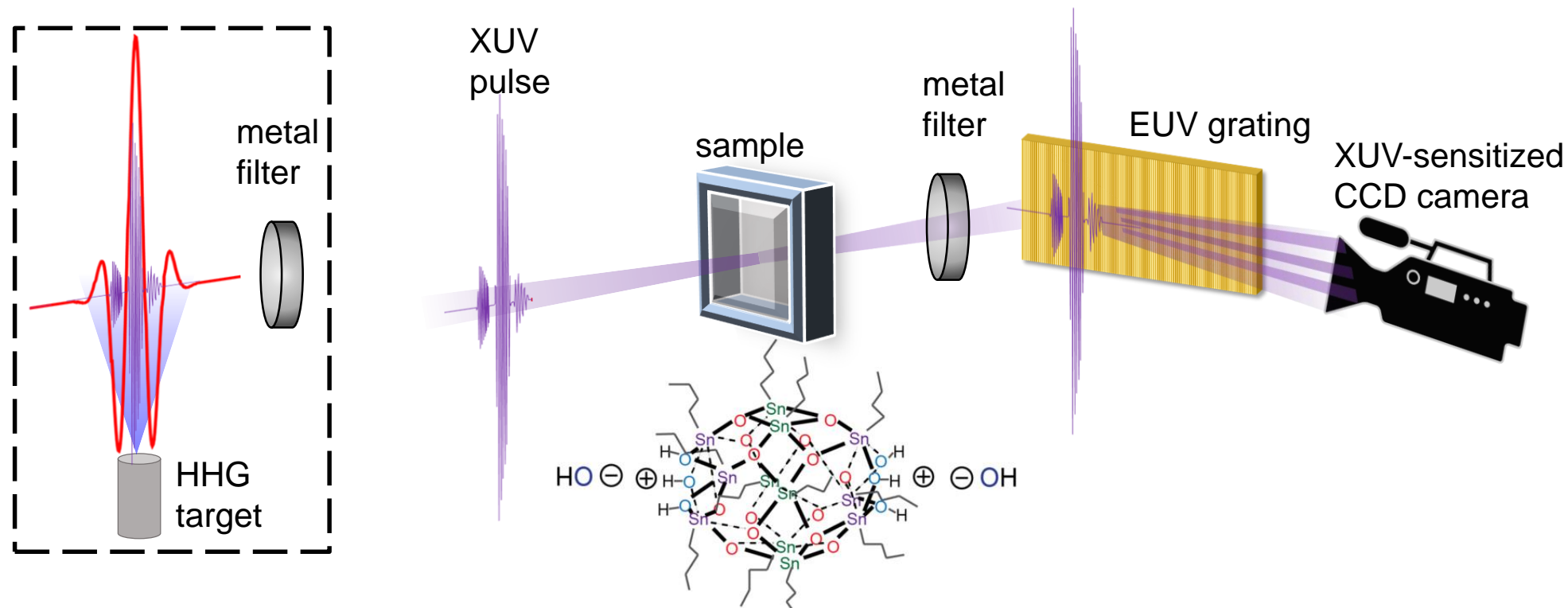
# Exposure kinetics of photoresists

---

- 1. Time-resolved extreme-ultraviolet transient absorption**
- 2. Time-resolved extreme/deep-ultraviolet luminescence**

# XUV Absorption and exposure in a single setup

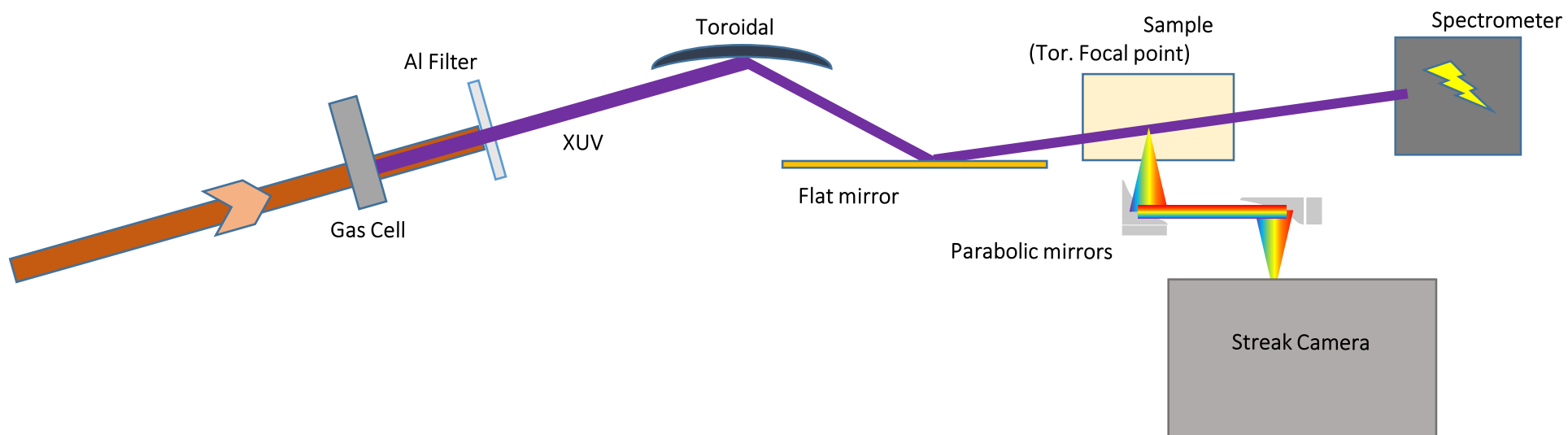
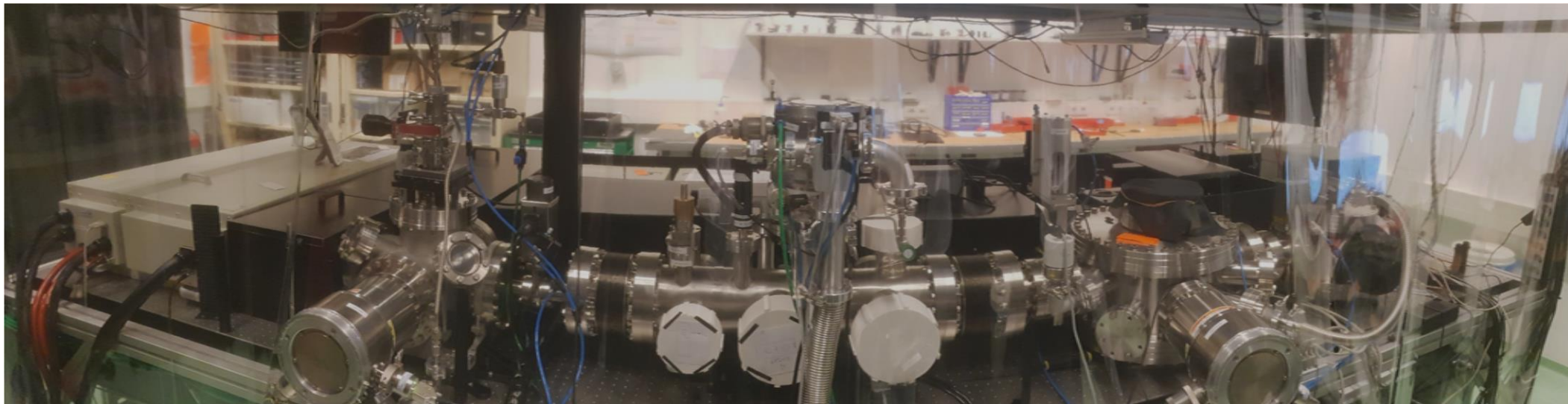
Measure the complex dynamics in materials relevant for EUV lithography and understand how to improve them.



**Unique feature of HHG-XANES: Simultaneous exposure and spectrally resolved absorption spectroscopy in the XUV with chemical sensitivity.**

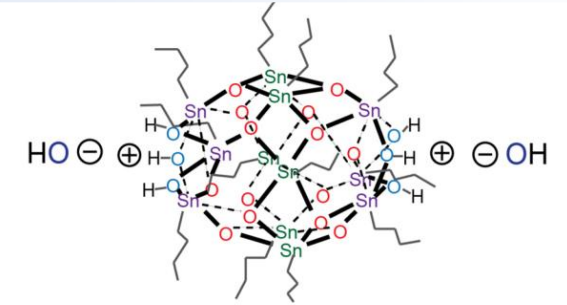
**Objective: Measure exposure kinetics as function of dose in photoresists.**

# Spectroscopy of EUV materials with HHG

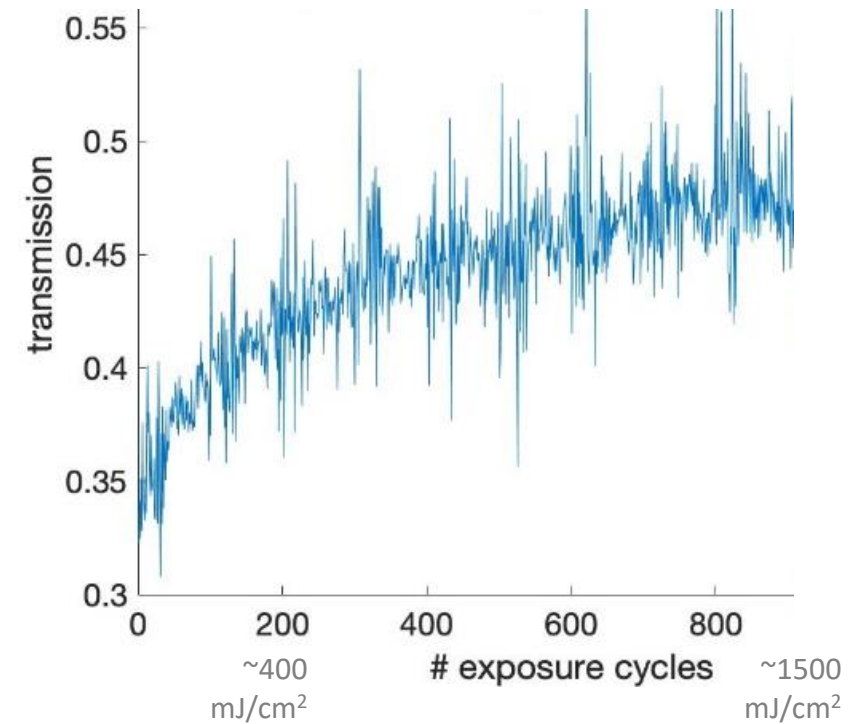
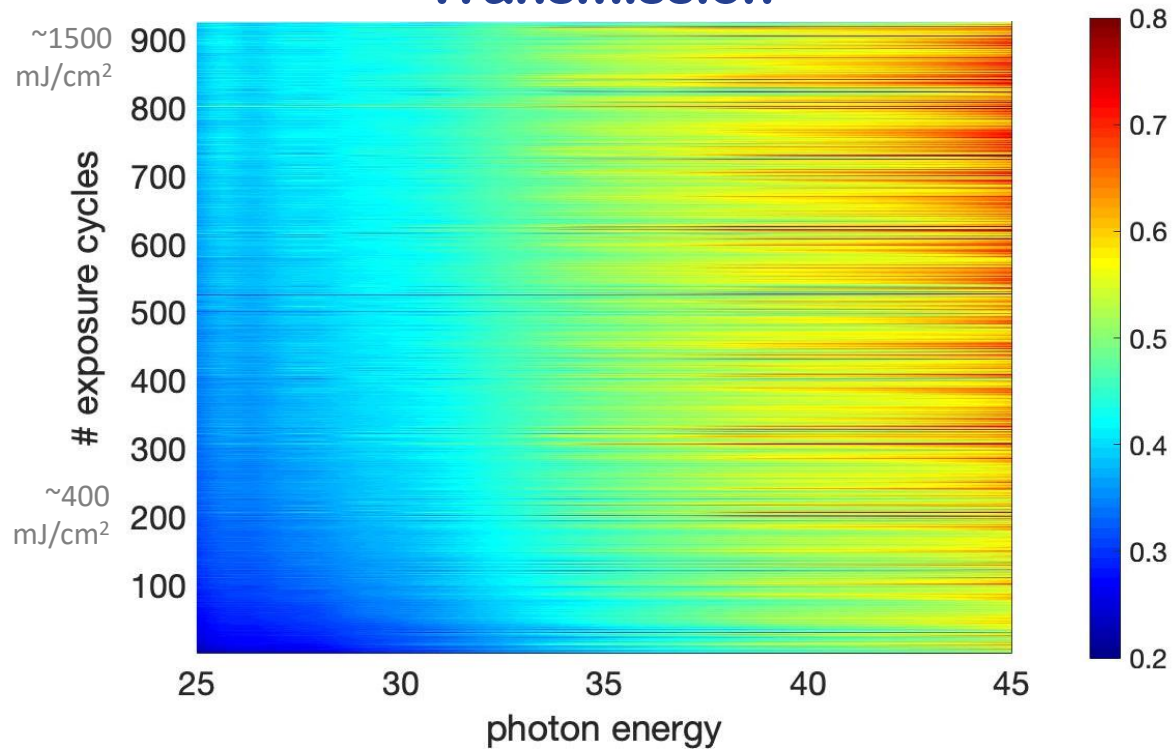


# XUV absorption tracks photochemistry

Exposure and absorption spectroscopy of tin-oxo cages from 25-45 eV: Follow 4d-LUMO transitions in Sn (25-30 eV).



### Transmission

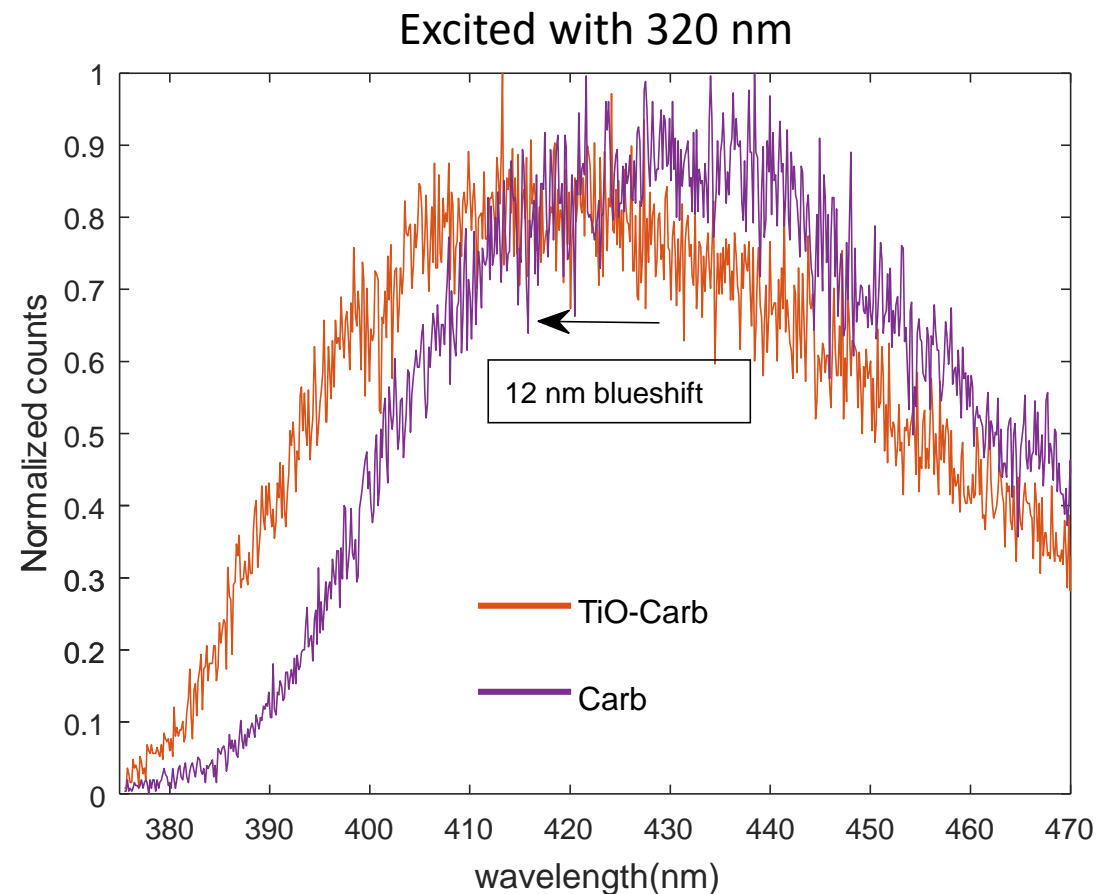
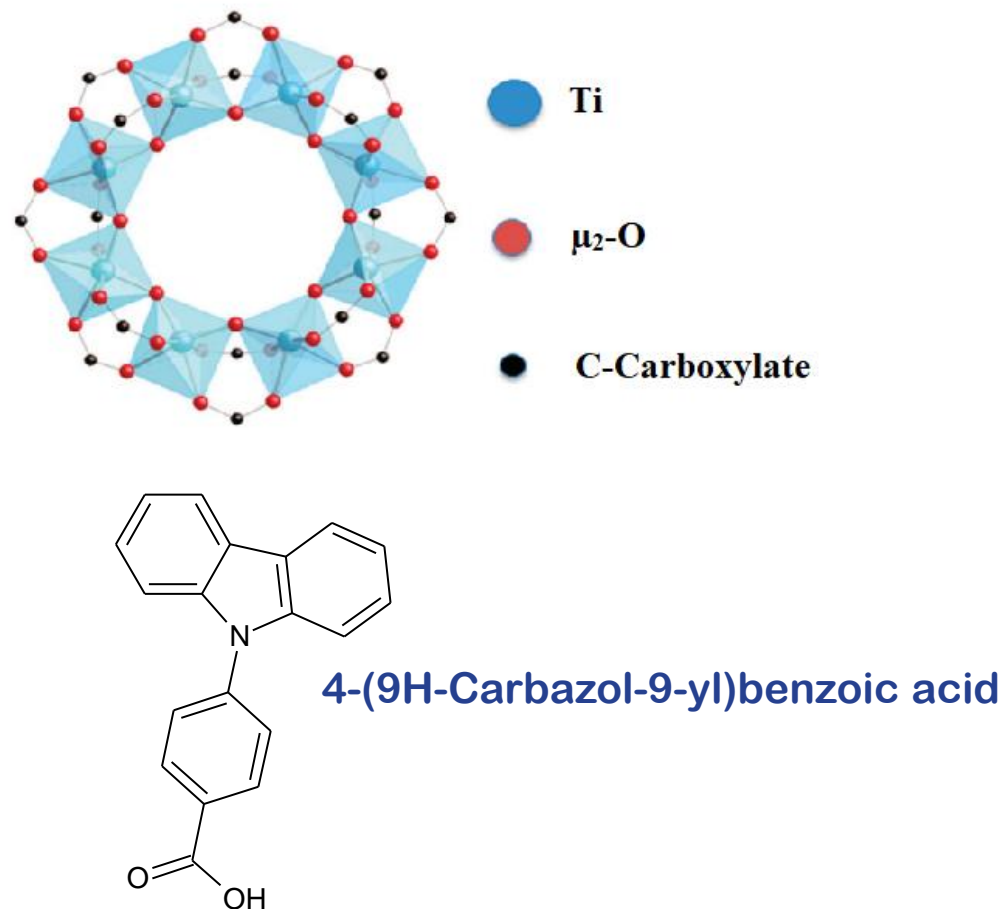


**Overall transmission increase: Butyl side chain dissociation.**

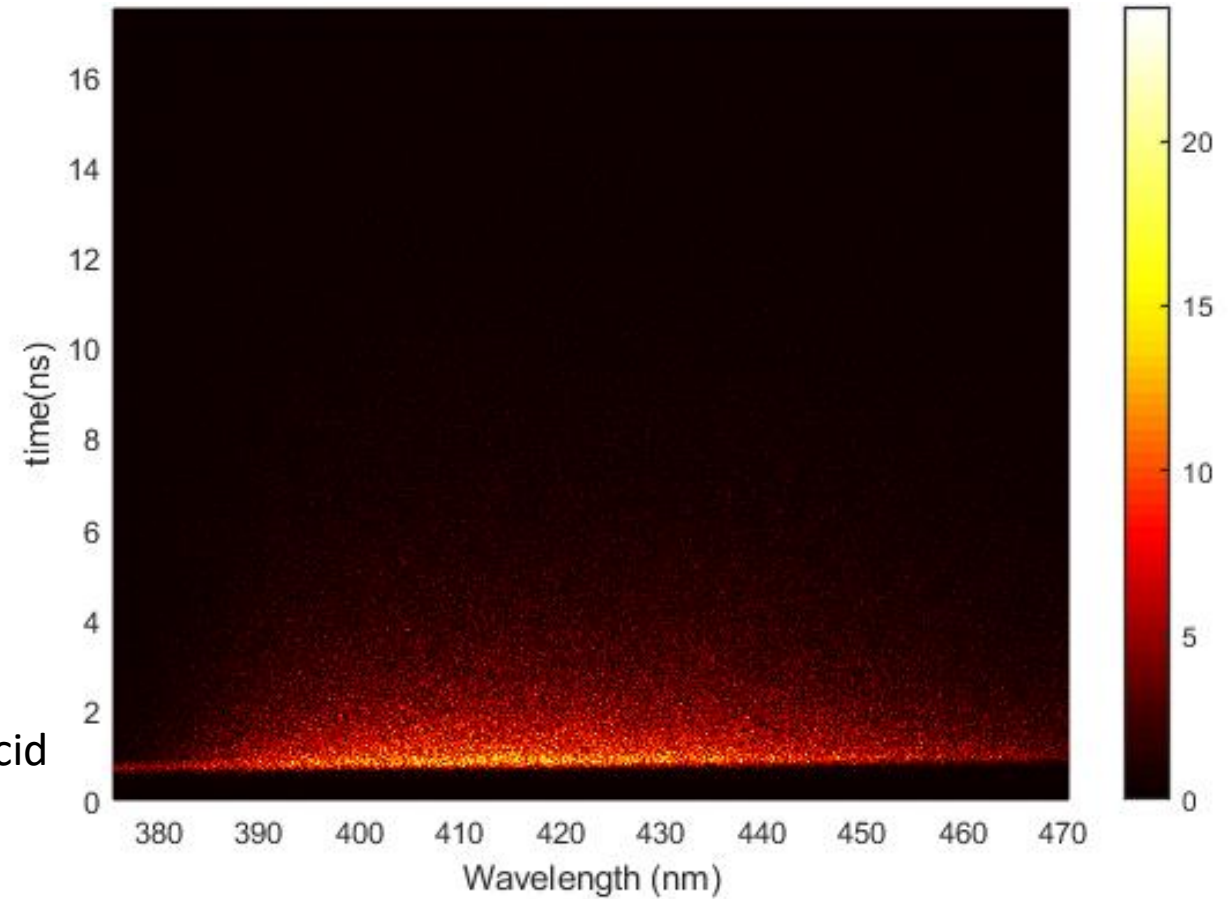
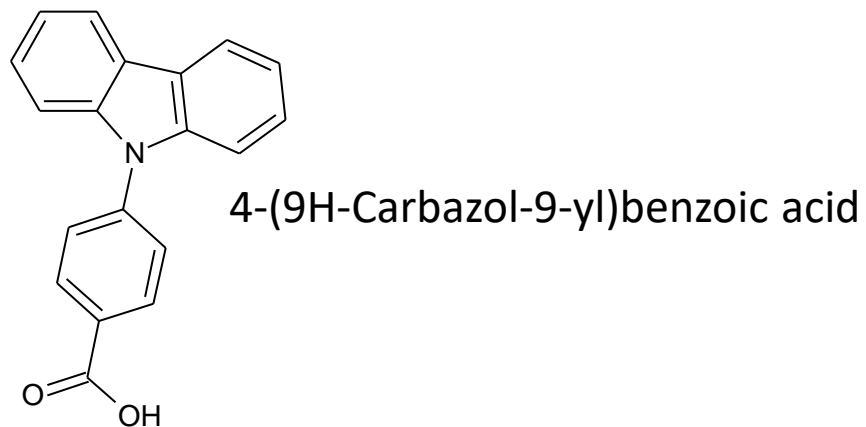
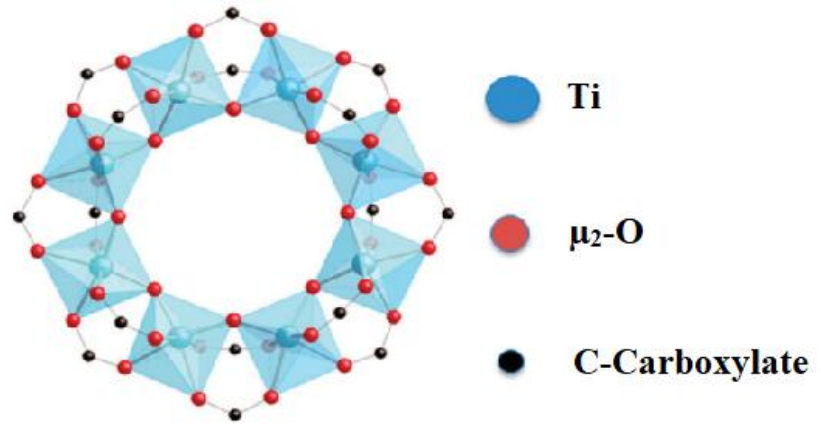
**Ongoing: Extraction of photoresist quantum yield**

# Luminescence of metal-oxo photoresists

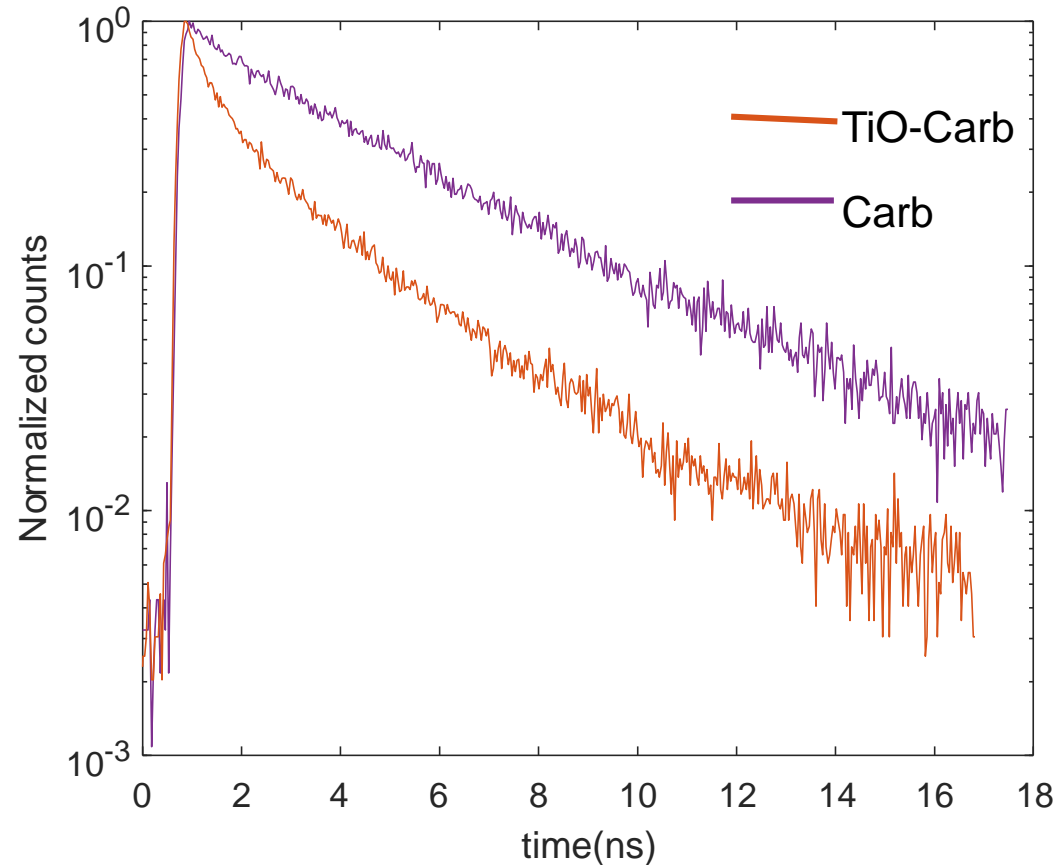
Energy converted into luminescence will not drive a chemical reaction.



# Time-resolving the luminescence



# Observation of sub-nanosecond radiative relaxation



Mono-exponential for Carbazol: 3.2 ns (Carb)

Bi-exponential for cluster: 0.54 & 2.8 ns (TiO-Carb)

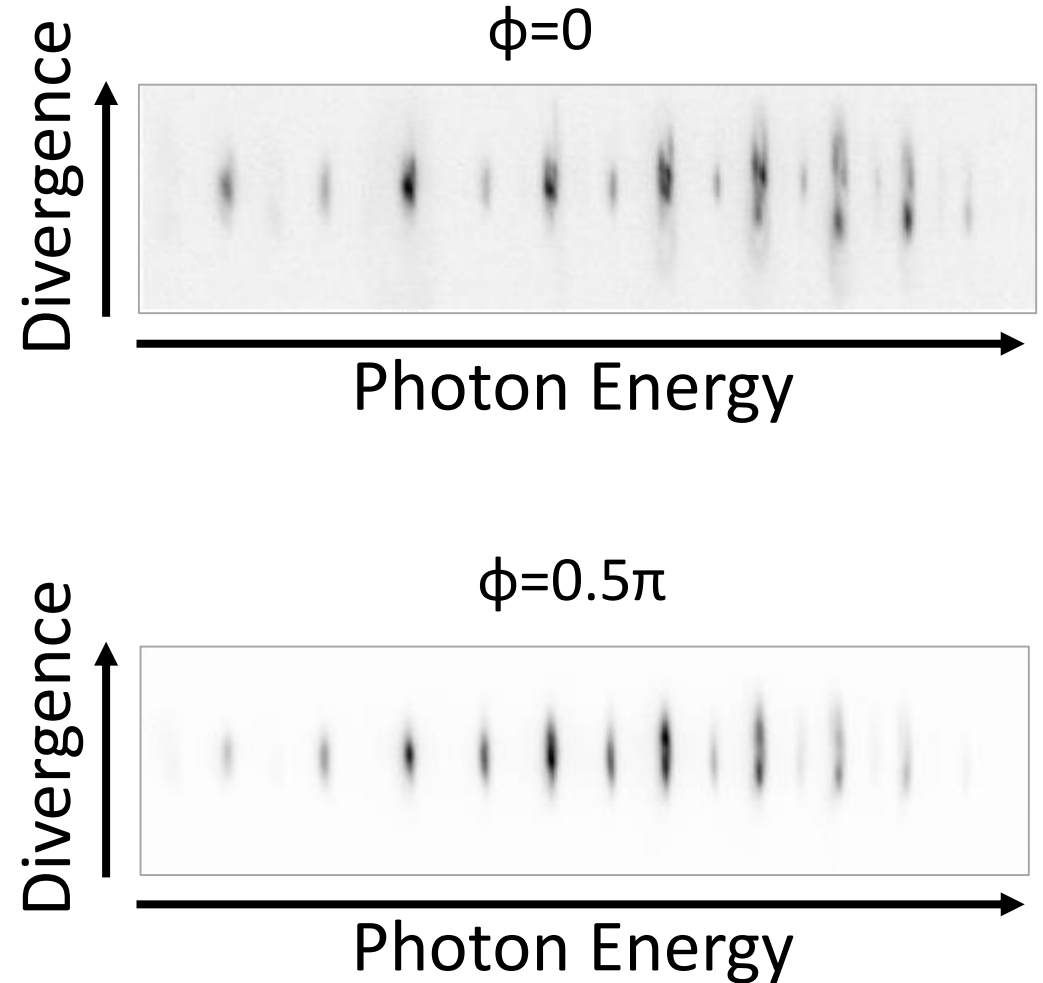
Possible hint at additional decay channel and charge transfer.

Ongoing: Extension of technique to extreme ultraviolet excitation.



# Conclusions

1. Developed experimental method for divergence control of high-harmonic generation.
2. Used table-top extreme ultraviolet absorption to follow the exposure kinetics of a photoresist.
3. Used time-resolved luminescence to identify alternative decay channels besides chemical reactions.



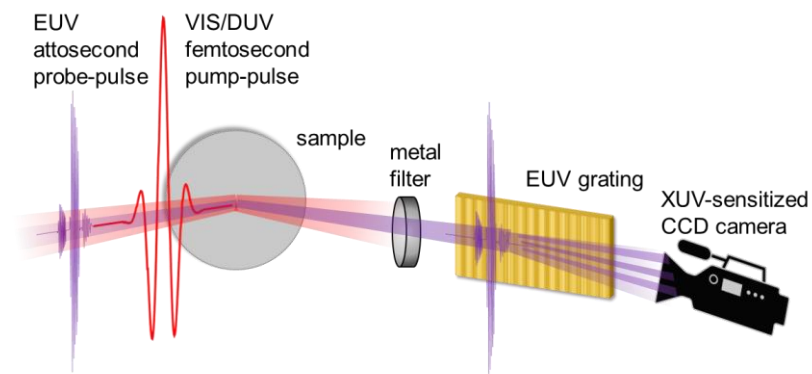
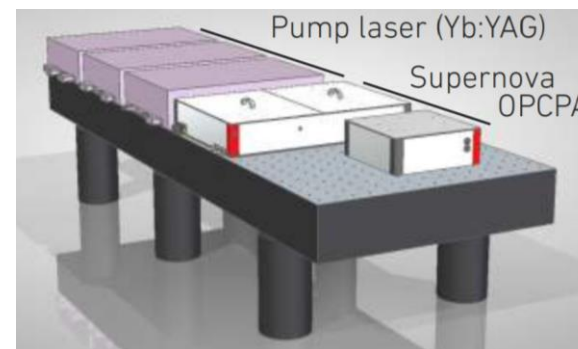
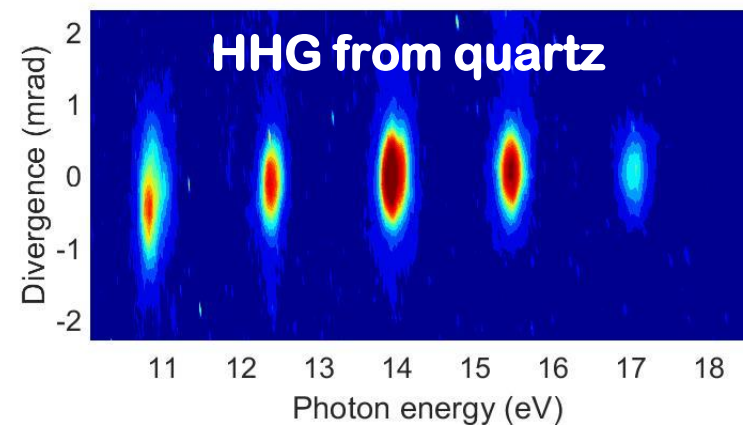
# Outlook

## New schemes for HHG:

- Solid-state HHG
- High-flux water-window soft x-ray HHG

## Time-resolved experiments on EUVL materials:

- Time-resolved XUV-excited optical luminescence
- Ultrafast pump-probe spectroscopy



# Thank You!

## HHG and EUV science group at ARCNL:

Sylvianne Roscam Abbing

Maarten van der Geest

Filippo Campi

Reinout Jaarsma

Najmeh Sadegh (not in picture,  
Brouwer group)

Faegheh Sajjadian (until Jan 2019)

ZhuangYan Zhang (not in picture)

Evelien Wooning (not in picture,  
until Aug 2019)

Alexandra Zeltsi (not in picture)

## Ongoing collaborations at ARCNL:

Sonia Castellanos

Fred Brouwer

